



Advanced electron and ion microscopy workshopp

A Microscopical Society of Canada (MSC) event
held at

Taylor room (public access area)
National Institute for Nanotechnology
11421 Saskatchewan Drive, Edmonton
GPS lat: 53.528498 long: -113.528017



Nov 5th 2014 presentations Coffee and donuts will be provided
Nov 6th 2014 demos and tours

Presentations, November 5th 2014

9 am Coffee and opening, Marie D'Iorio, NINT.

9:15 am – 10 am

Accuracy and applications of electron-beam deposited nano-dot fiducial markers in electron tomography of rod-shaped specimens.

Misa Hayashida

National Institute of Advanced Industrial Science and Technology, Tsukuba, Japan.

10:15 – 11 am

The late breaking news about TEM application software

Hiromitsu Furukawa

Systems in Frontier Inc., Tokyo, Japan.

11:15 am – 12 noon

Characterization for materials structures on an atomic scale with an aberration optimized TEM/STEM

Masahiro Kawasaki

JEOL USA Inc. Peabody, USA.

12 noon – 1:15 pm lunch break

1:15 pm – 2 pm

The Orion Nanofab Helium Ion Microscopy (HiM) – imaging, nanofabrication, and applications

Diane Stewart,

Carl Zeiss USA.

2:15 pm – 3 pm

Cleaning up the Microscope world

David Hoyle

Hitachi High Technologies Canada, Toronto, Canada

3:15 pm – 4 pm

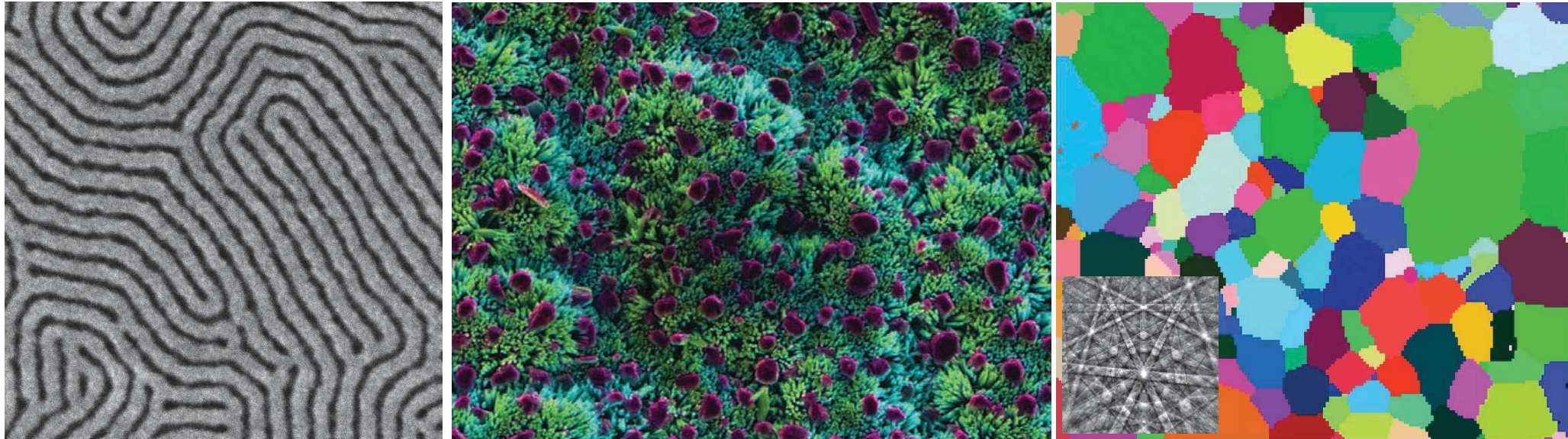
Very large solid Angle Silicon Drift Detectors for EDS Analysis on both SEM and TEM

Neil Rowlands,

Oxford Instruments, Canada

Tour/Demonstration, November 6th 2014

University of Alberta nanoFAB Facility, W1-060 ECERF Building, 116 Street & 85 Avenue



- 1. Tour of nanoFAB cleanroom and Helium Ion Microscopy (HiM) lab**
- 2. Demo of Zeiss Sigma FESEM (6 sessions, 10 spots each session)**
 - Low Voltage SEM imaging: 9-10 am, 1-2 pm**
 - EDX: 10-11 am, 2-3 pm**
 - EBSD: 11-12 pm, 3-4 pm**

nanoFAB will be pleased to offer user sample runs if arrangement is made prior to the workshop and time permits.
Please contact Peng Li (peng.li@ualberta.ca) if interested.